

<b>Electronic Patent Application Fee Transmittal</b>				
<b>Application Number:</b>	10751898			
<b>Filing Date:</b>	07-Jan-2004			
<b>Title of Invention:</b>	Plasma processing apparatus and focus ring			
First Named Inventor/Applicant Name:	Shosuke Endoh			
<b>Filer:</b>	Marvin Jay Spivak/LaKisha Durham			
<b>Attorney Docket Number:</b>	247409US2			
Filed as Large Entity				
<b>Utility Filing Fees</b>				
Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
<b>Basic Filing:</b>				
<b>Pages:</b>				
<b>Claims:</b>				
Claims in excess of 20	1202	4	50	200
<b>Miscellaneous-Filing:</b>				
<b>Petition:</b>				
<b>Patent-Appeals-and-Interference:</b>				
<b>Post-Allowance-and-Post-Issuance:</b>				
<b>Extension-of-Time:</b>				

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Extension - 3 months with \$0 paid	1253	1	1050	1050
<b>Miscellaneous:</b>				
<b>Total in USD (\$)</b>				<b>1250</b>